

## **AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

## Listing of Claims:

- 1. (currently amended): A method of producing a thick nonlinear optical grating [[(2)]] with a thickness of several hundred microns from an initial thick nonlinear optical grating [[(1)]], the thickness [[(E<sub>2</sub>)]] of the nonlinear optical grating [[(2)]] being greater than the thickness [[(E<sub>0</sub>)]] of the initial nonlinear optical grating [[(1)]], said initial grating comprising at least one plurality of mutually parallel plane layers [[(20)]], said layers having at least two nonlinear coefficients having algebraically different values, said initial grating having a first face [[(11)]] and a second face [[(12)]] that are approximately parallel to each other and approximately perpendicular to the mean plane of the layers, and said second face [[(12)]] being free, comprising characterized in that it comprises the following production steps:
- [[•]] a first step of determining the thickness [[( $E_{01}$ ,  $E_{02}$ )]] of that upper part of the initial grating [[(1)]] which lies beneath the second face [[(12)]], which upper part has structural imperfections;
- [[•]] a second step of polishing the second face [[(12)]] of said initial grating [[(1)]], making it possible to remove the upper part having said imperfections and to obtain a polished and plane third face [[(13)]], said face approximately perpendicular to the mean plane of the layers [[(20)]];
  - [[•]] a third step of cleaning and checking said third face [[(13)]]; and
- [[•]] at least a fourth step of epitaxially depositing at least one layer [[(1a, 1b)]] of material deposited on said third face [[(13)]], the epitaxial growth reproducing, in said deposited layer, a structure similar to that of the initial grating, the combination of the initial grating [[(1)]] and said deposited layer [[(1a, 1b)]] constituting the nonlinear optical grating [[(2)]].



- 2. (currently amended): The method of producing an optical grating [[(2)]] as claimed in claim 1, eheracterized in that wherein the means of determining the thickness having imperfections are optical display devices.
- 3. (currently amended): The method of producing a nonlinear optical grating [[(2)]] as claimed in either of the preceding claim[[s]] 1, characterized in that wherein after the second production step, the thickness [[( $E_1$ )]] of the initial optical grating is at least 50 microns.
- 4. (currently amended): The method of producing a nonlinear optical grating [[(2)]] as claimed in claim 1, characterized in that wherein the initial nonlinear optical grating [[(1)]] is supported by a seed substrate [[(3)]] having a lower face [[(14)]] and a plane upper face [[(11)]], the upper face [[(11)]] of the seed substrate coinciding with the first face [[(11)]] of said initial nonlinear optical grating [[(1)]].
- 5. (currently amended): The method of producing a nonlinear optical grating [[(2)]] as claimed in claim 4, characterized in that wherein the seed substrate [[(3)]] comprises a crystalline material having a first crystal orientation, the upper face [[(11)]] of the seed substrate having a thin structure, said structure being formed from a precursor grating of parallel bands of the same crystalline material but of the opposite orientation to that of the seed substrate [[(3)]].
- 6. (currently amended): The method of producing a nonlinear optical grating [[(2)]] as claimed in claim 5, characterized in that wherein the thickness of the seed substrate [[(3)]] is at least 300 microns.
- 7. (currently amended): The method of producing an optical grating [[(2)]] as claimed in claim 4, characterized in that wherein [[the]] said second production step includes comprises the following preliminary steps:
  - [[•]] a first preliminary step of polishing the lower face [[(14)]] of the substrate; and
- [[•]] a second preliminary step of bonding at least said lower face [[(14)]] to at least one plane support [[(32)]], the fitting of the support making it easier to handle the initial optical

grating [[(1)]] for the subsequent polishing operations.

- 8. (currently amended): The method of producing a nonlinear optical grating [[(2)]] as claimed in claim 4, eharacterized in that wherein the initial nonlinear optical grating [[(1)]] is obtained by the epitaxial growth method called HVPE (hydride vapor phase epitaxy) on the upper face of the seed substrate [[(3)]].
- 9. (currently amended): The method of producing an optical grating [[(2)]] as claimed in claim 1, characterized in that wherein the method of producing the initial nonlinear optical grating [[(1)]] includes comprises the following substeps:
- [[•]] a first substep of producing a stack of crystalline plates [[(21)]] having plane parallel faces, of the same material, of small thickness and of periodically alternating crystal orientation; and
- [[•]] a second substep of assembling said crystalline plates so as to obtain a single monolithic assembly [[(1)]] constituting the initial optical grating, said initial grating having a first face [[(11)]] and a second face [[(12)]] that are approximately perpendicular to the mean plane of the crystalline plates.
- 10. (currently amended): The method of producing an optical grating as claimed in claim 9, characterized in that wherein [[the]] said second step in the production of the initial grating [[(2)]] is preceded by the following preliminary steps:
- a first preliminary step of polishing the first face [[(11)]] of the monolithic stack; and
- [[•]] a second preliminary step of bonding at least said first face [[(11)]] to at least one plane support [[(32)]], the fitting of the support making it easier to handle the monolithic assembly for the subsequent operations of polishing the second face [[(12)]].
- 11. (currently amended): The method of producing an optical grating [[(2)]] as claimed in one of the preceding claim[[s]] 1, characterized in that wherein, during [[the]] said fourth production step, at least two layers [[(1a, 1b)]] of materials of different optical index are

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deposited so as to form an optical waveguide.

- 12. (currently amended): The method of producing a nonlinear optical grating [[(2)]] as claimed in one of the preceding claim[[s]] 1, characterized in that wherein during [[the]] said fourth production step, at least one of the layers [[(1a, 1b)]] is obtained by the epitaxial growth method called OMCVD (organometallic chemical vapor deposition) or by MBE (molecular beam epitaxy).
- 13. (new): The method of producing a nonlinear optical grating as claimed in claim 2, wherein after [[the]] said second production step, the thickness of the initial optical grating is at least 50 microns.

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